

Form PTO-1449 (MODIFIED)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. 39153/325 (F0853)	SERIAL NO. Unknown
INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)		APPLICANT Babcock et al.	
		FILING DATE Unknown	GROUP ART UNIT Unknown

100-04760
USPTO
07/15/02

U.S. PATENT DOCUMENTS

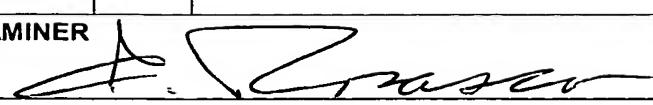
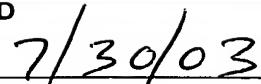
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION
							YES NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

		Douglas Van Den Broeke, Transferring Phase-Shifting Mask Technology into Mainstream Manufacturing, printed from Internet address: http://www.semiconductorfabtech.com/f...s/lithography/articles/body5.225.php3 on October 6, 2000, 7 pages
		Andrew B. Kahng et al., Subwavelength Lithography and its Potential Impact on Design and EDA, 6 pages

EXAMINER 	DATE CONSIDERED 
--	---

* EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include any copy of this form with next communication to applicant.